

## Construction of Demonstrator

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LAL Orsay

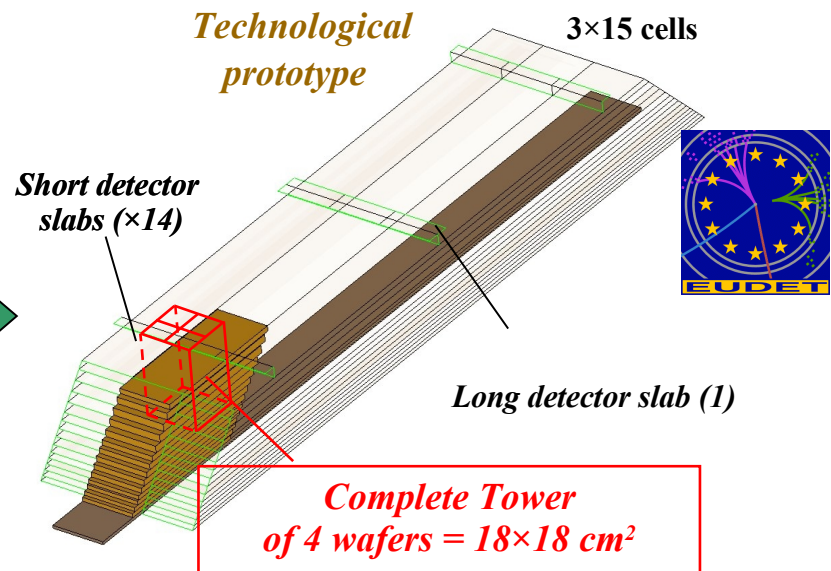
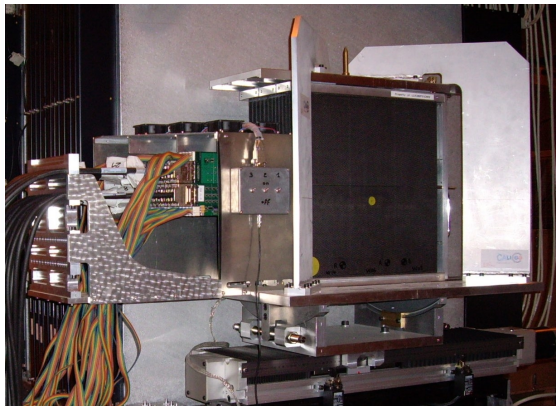
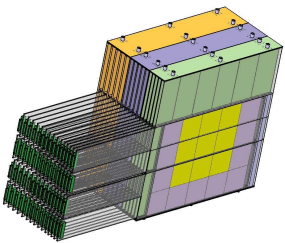
Summary of activities to underline contributions  
by the various groups

To learn more ....

<http://flc.web.lal.in2p3.fr/poeschl/siwecal.html>

# EUDET Prototype

- **Logical continuation** to the physical prototype study which validated the main concepts : alveolar structure , slabs, gluing of wafers, integration
- Techno. Proto : study and validation of most of **technological solutions** wich could be used for the final detector (moulding process, cooling system, wide size structures,...)
- Taking into account **industrialization aspect** of process
- First **cost** estimation of one module



- **3 structures : 24 X<sub>0</sub>**  
(10×1,4mm + 10×2,8mm + 10×4,2mm)
- **sizes : 380×380×200 mm<sup>3</sup>**
- **Thickness of slabs : 8.3 mm**  
(W=1,4mm)
- **VFE outside detector**
- **Number of channels : 9720 (10×10 mm<sup>2</sup>)**
- **Weight : ~ 200 Kg**

- **1 structure : ~ 23 X<sub>0</sub>**  
(20×2,1mm + 9×4,2mm)
- **sizes : 1560×545×186 mm<sup>3</sup>**
- **Thickness of slabs : 6 mm**  
(W=2,1mm)
- **VFE inside detector**
- **Number of channels : 45360 (5×5 mm<sup>2</sup>)**
- **Weight : ~ 700 Kg**

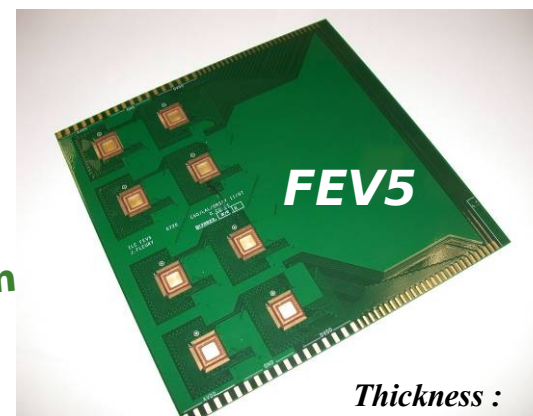
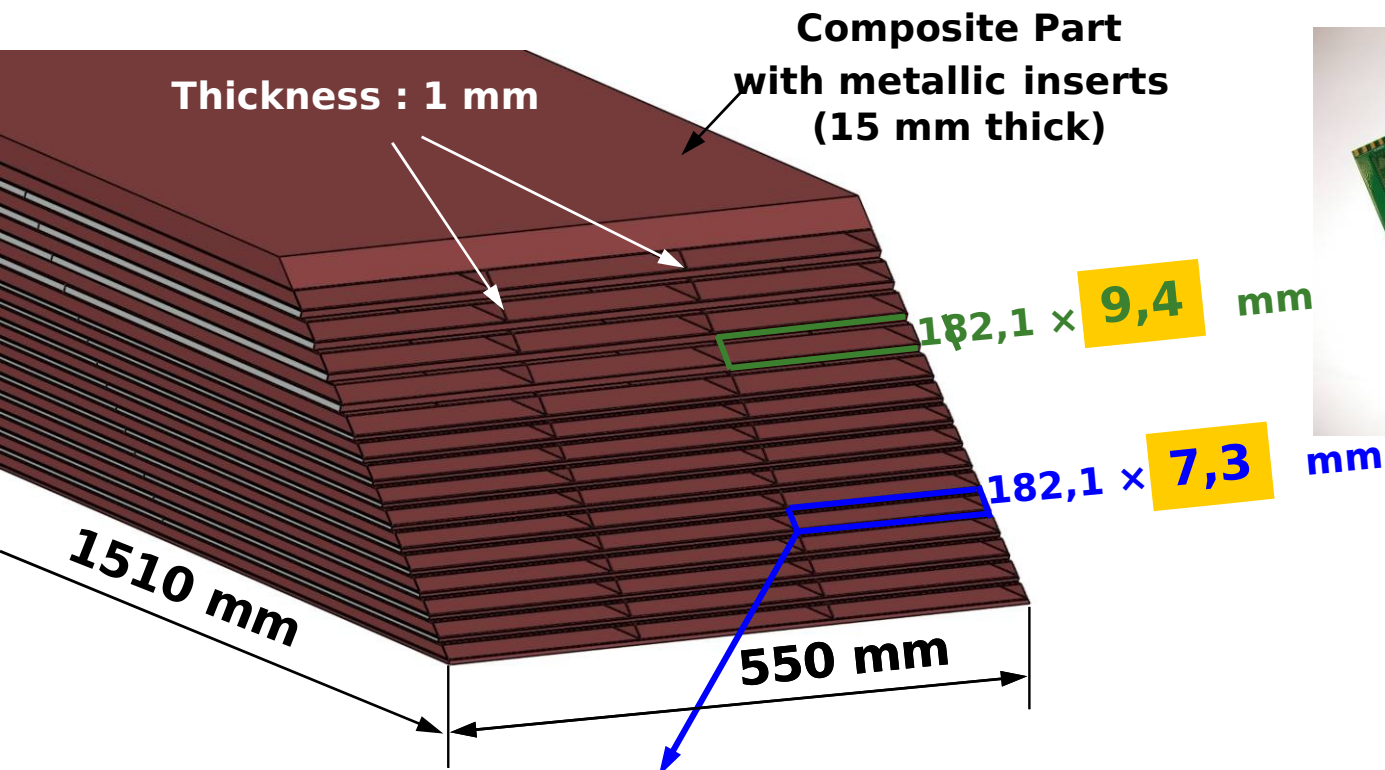
cal Meet

# The groups working on the EUDET Electromagnetic Calorimeter



- What we call “EUDET Module” is in fact the next SiW Ecal CALICE Prototype
- Financial support by EU but largest fraction of funding still from “Calice” resources!!!!

# Module EUDET – Current Design (final)

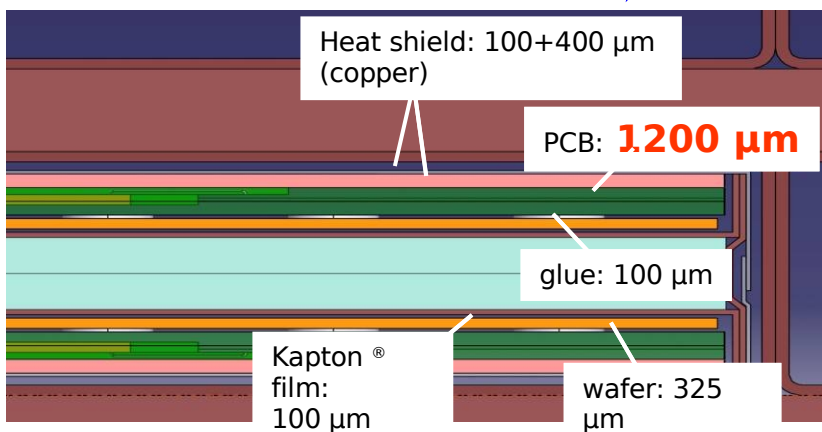


Thickness :

FEV5-1 : 1.17mm (+-0.04)

FEV5-2 : 1.19mm (+-0.04)

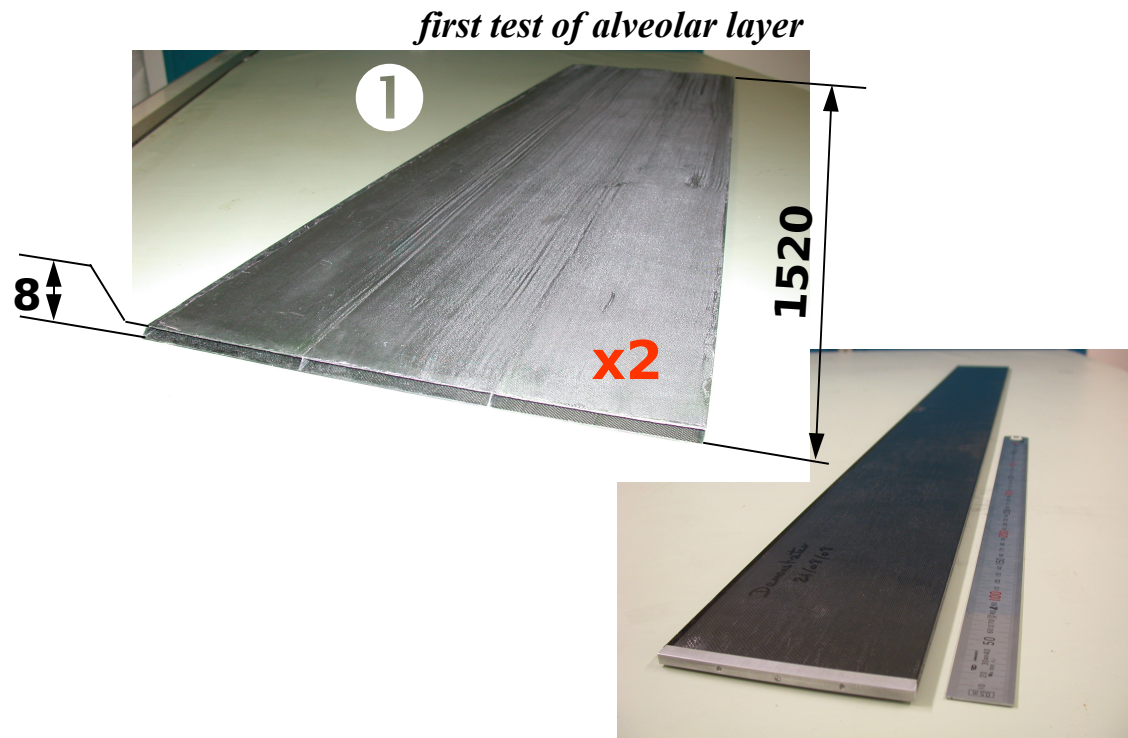
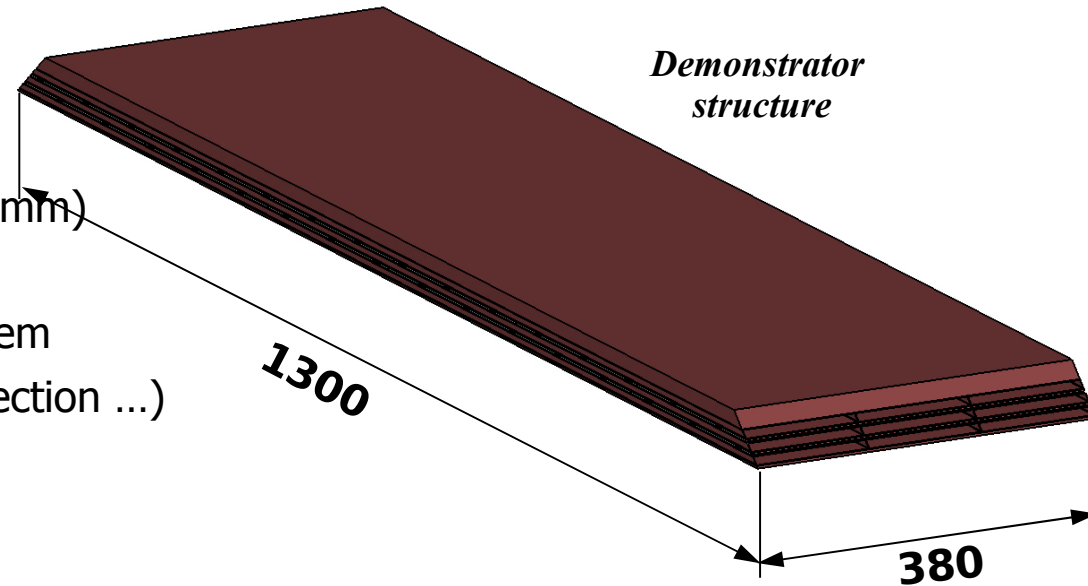
FEV5-3 : 1.20mm (+-0.02)



- ⇒ Gaps (slab integration) : 500  $\mu\text{m}$
- ⇒ Heat Shield: 400  $\mu\text{m}$  ? Validation with the demonstrateur
- ⇒ PCB : 800  $\mu\text{m}$  ~~~1200  $\mu\text{m}$~~
- ⇒ Thickness of Glue : 100  $\mu\text{m}$
- ⇒ Thickness of SiWafer : 325  $\mu\text{m}$
- ⇒ Kapton® film HV : 100  $\mu\text{m}$  ?
- ⇒ Thickness of W : 2100/4200  $\mu\text{m}$  ( $\pm 80 \mu\text{m}$ )

# Demonstrator design

- We have constructed a **demonstrator** to validate the assembly process before the actual EUDET Module
- Width the same as for physics prototype (124 mm)
- **Thermal Studies:** Equipped with thermal PCBs and a cooling system
- First test of **slab** integration (gluing, interconnection ...)



- **3** alveolar layers + **2** W layers
- **3** columns of cells : representative cells in the middle of the structure
- **Thermal studies** support
- **Width of cells : 126 mm**
- **Identical global length : 1.3m** and shape (trapezoidal)
- **Fastening system ECAL/HCAL**

# Parties Involved

**6 Laboratories** are sharing out tasks in according to preferences and localization:

Assembling of **A.S.U.** (industrialization, gluing and tests) + backend system (DIF support) + services



Tests of **wafers**  
Global **Design** + composite **Structures**



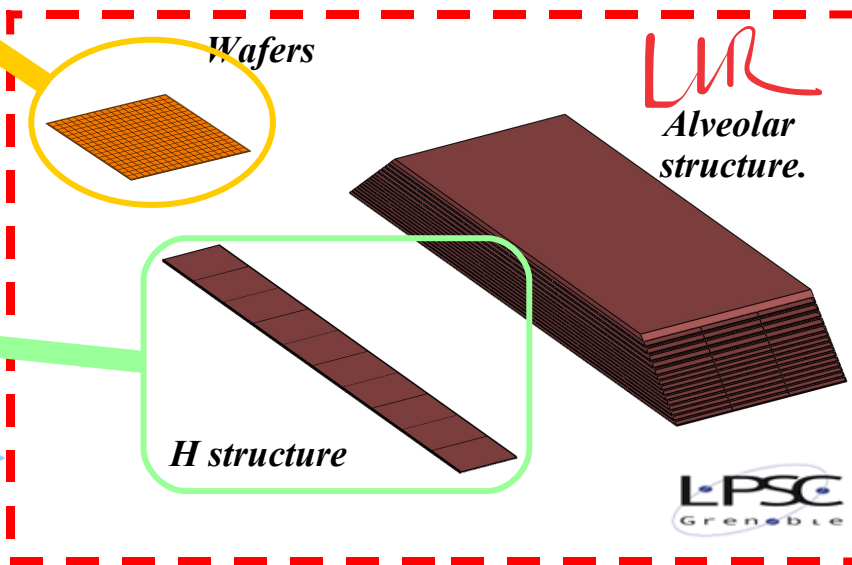
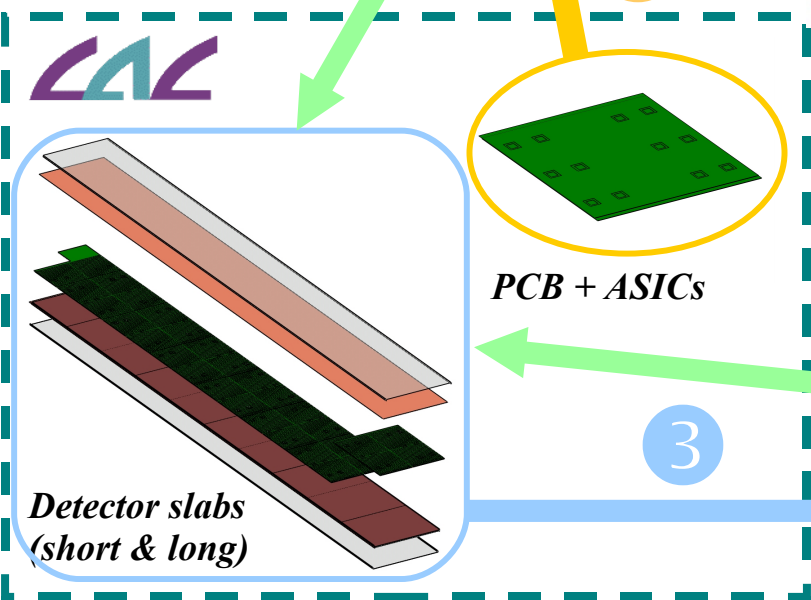
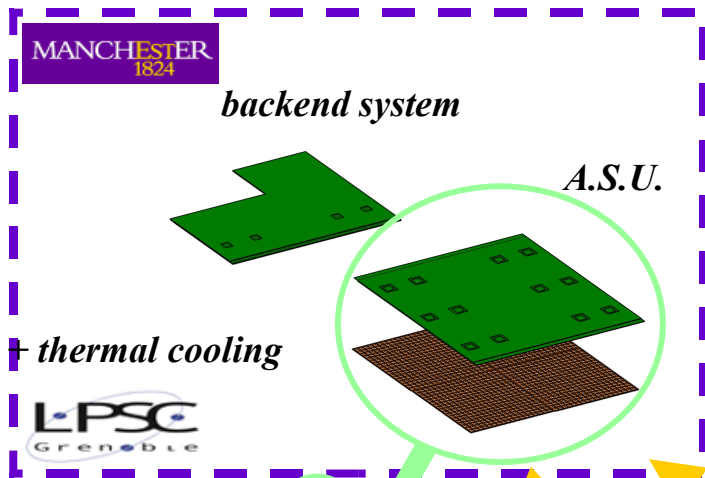
Thin PCB with embedded ASICs  
**Detector slabs** integration



External cooling system  
**Fastening system** ECAL/HCAL+composite plates



**Interconnection** of ASU, DIF



2

1

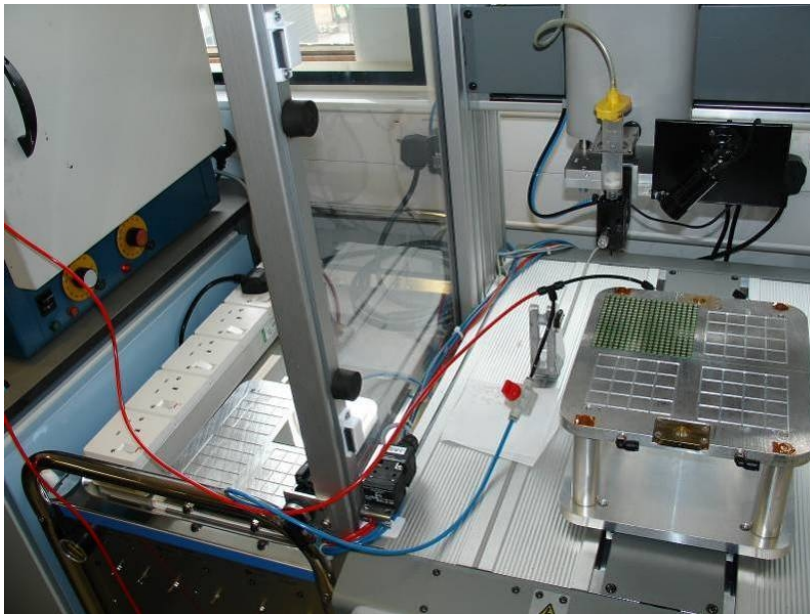
2

3

# Gluing of ASUS

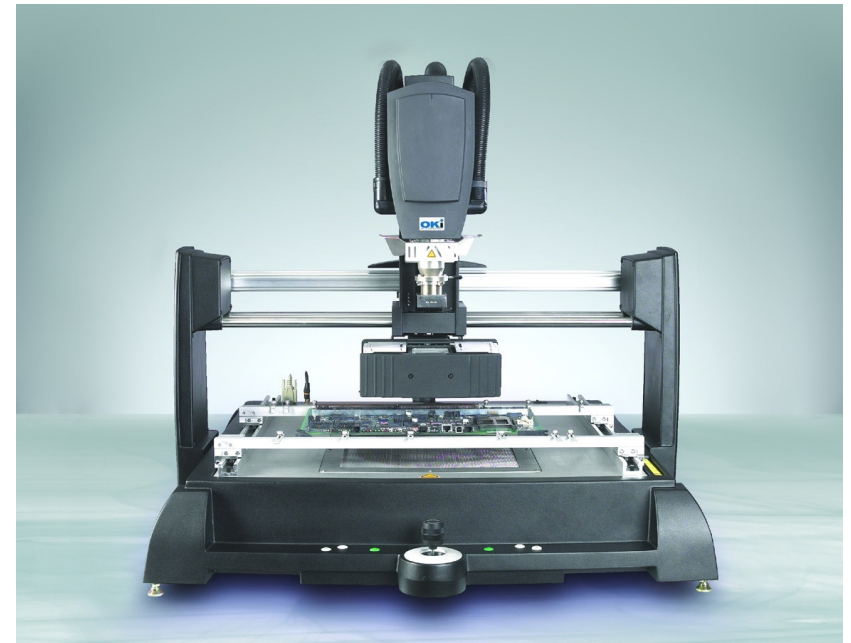
- Controlled glue dot deposition on the PCB
- The (four) Si Wafers are picked up, aligned and placed on the PCB
- Accurate thickness and planarity control via vacuum jigs
- The assembled ASU is allowed to cure

Test board with Dispenser Robot



“Gluing” rate 0.4 Hz

BGA Workstation for Wafer Placement



Precise Wafer Placement  
by Split Field Optics

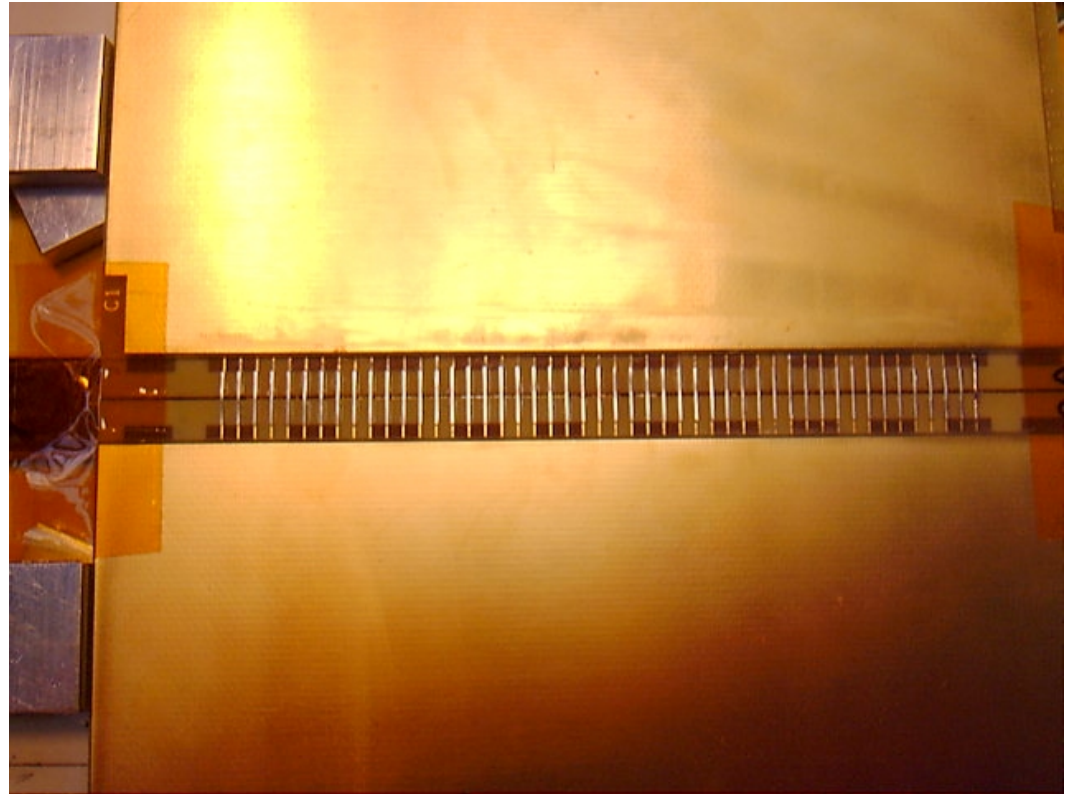
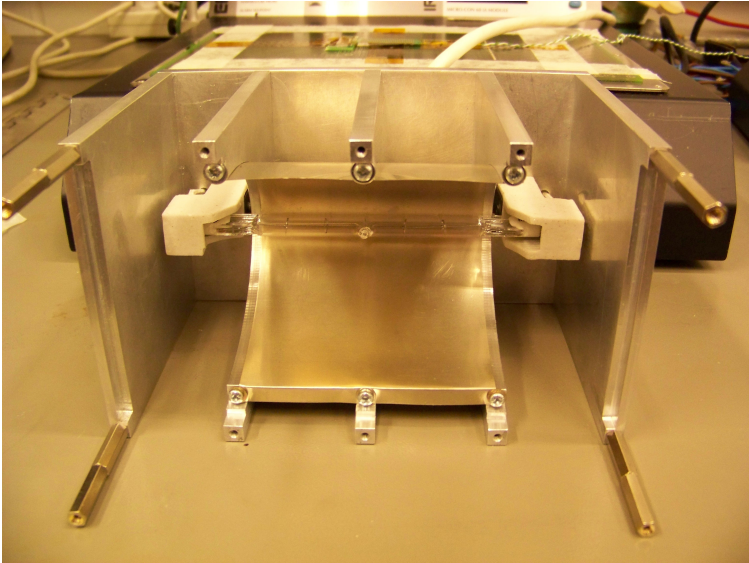
ASUs for four thermal layers glued at Uni Manchester

## Workshop with H and Thermal Boards

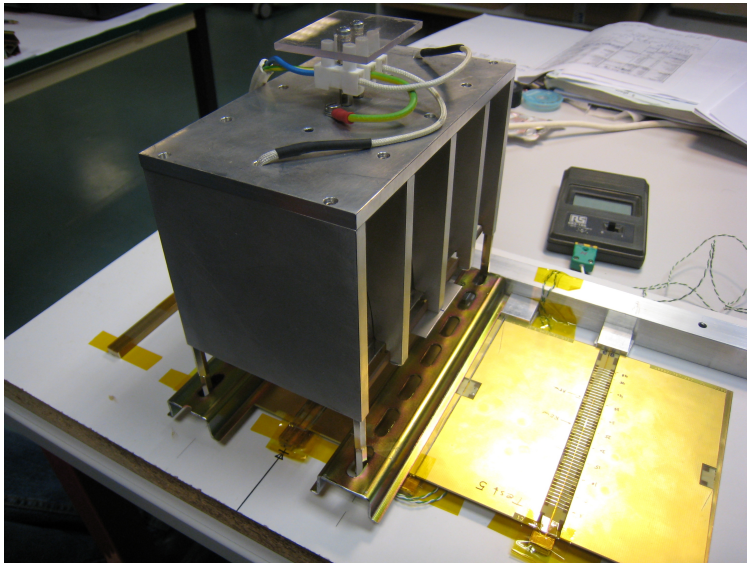




## The joint between two boards

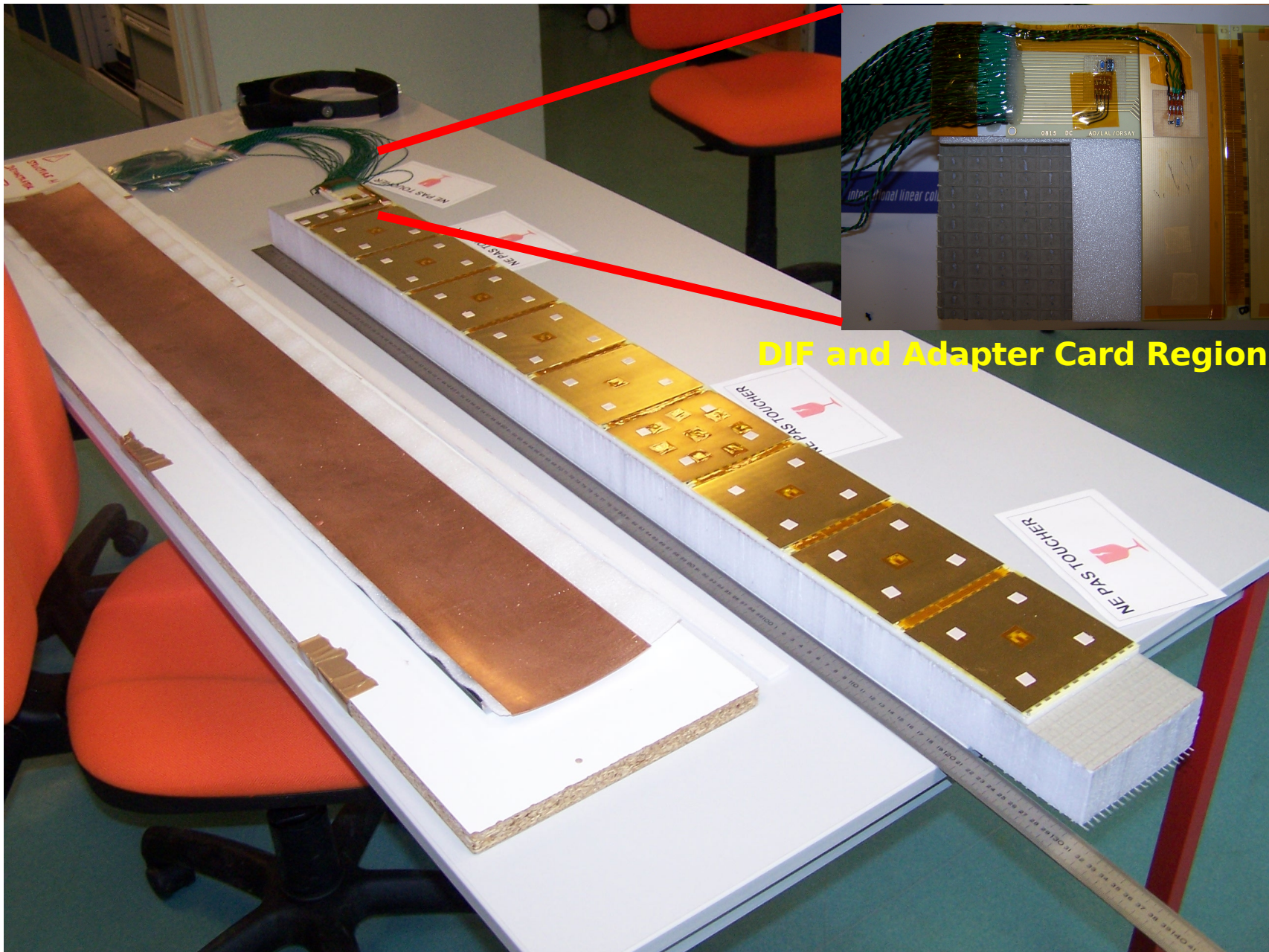


- Joint by halogen lamp heating up tin-bismuth soldering paste (Method developed by U. Cambridge)
- Heating Temperature  $\sim 200^{\circ}\text{C}$



**Delicate Process for Demonstrator – Easier for EUDET Module**

# Thermal Layer and (bended) Copper Shield

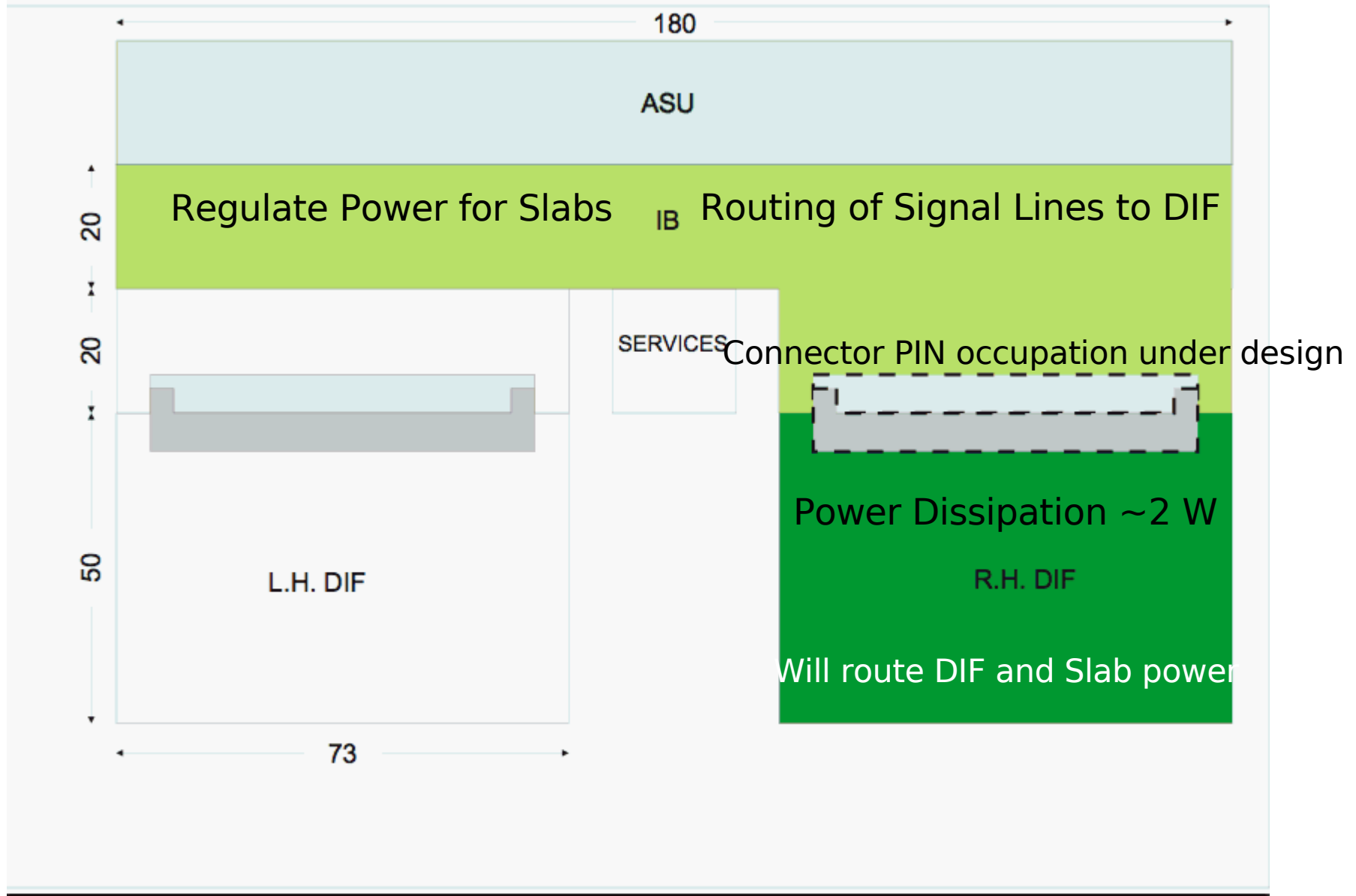


**DIF and Adapter Card Region**

Details by J. Bonis

*SiW Ecal Meeting June 2009*

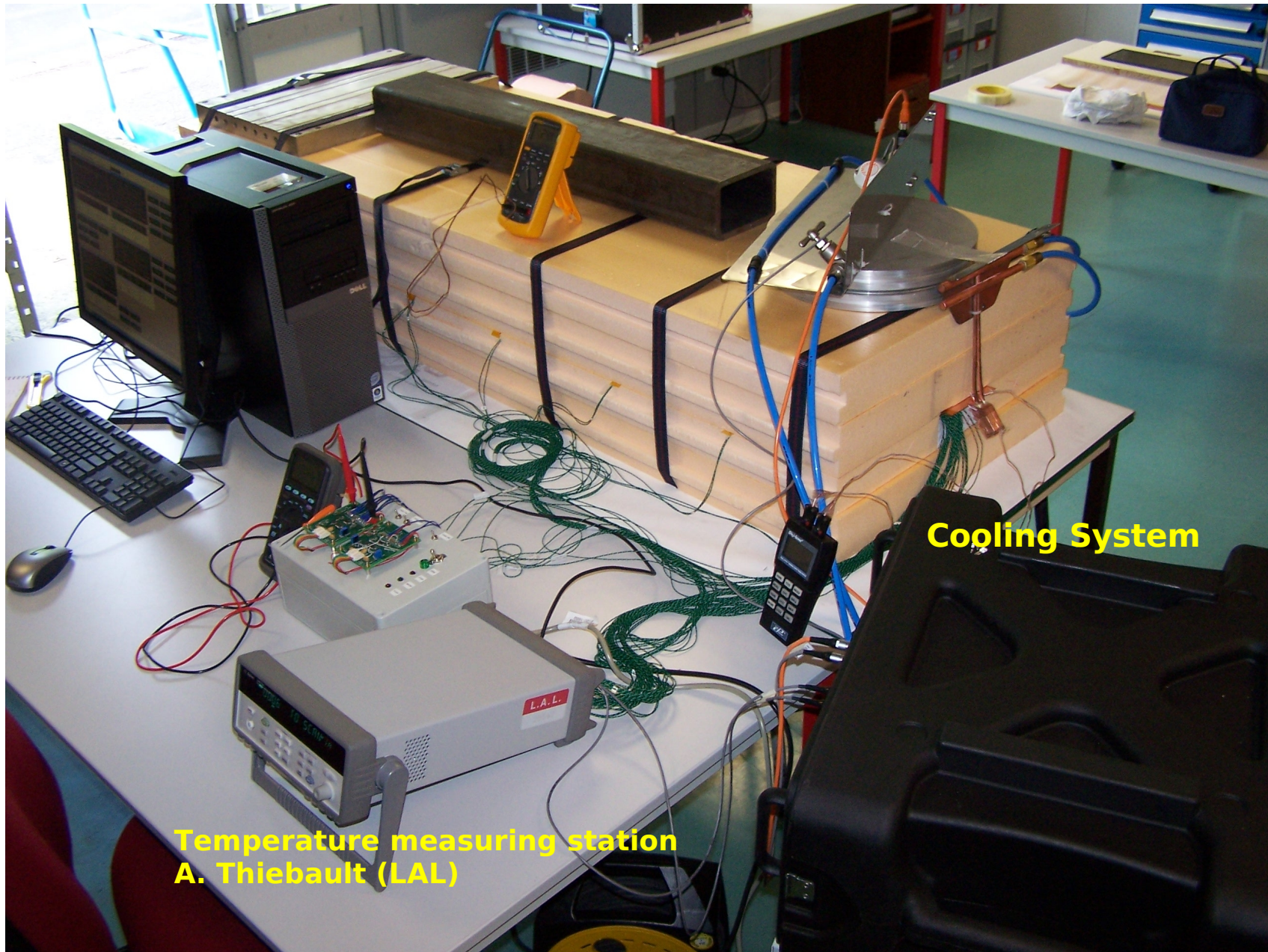
# Intermezzo - Agreed Dimensions DIF/IB Region



More in talk by Bart today and Electronics Meeting tomorrow

Performing the thermal tests – May 2009

**Improved insulation w.r.t. To February test**



**Cooling System**

**Temperature measuring station  
A. Thiebault (LAL)**

# Snapshot of measurements during thermal tests

Setup 05/18/09 09:33:41 - Data 05/19/09 10:43:46 - Agilent BenchLink Data Logger

File Edit View Scan Channel Graphics Instrument Help

None Off

Strip Chart

Channel Name	Units/Div	Reference	Marker: 1	Marker: 2
6 <107>Externe 7	0.500000 C	25.07135 C	Off	Off
7 <108>Externe 8	0.500000 C	21.27528 C	Off	Off

Time/Div: 02:00min y2:(Off) l2:(Off)  
y1:(Off) t1:(Off)  
Delta y: Delta t:

Strip Chart

Channel Name	Units/Div	Reference	Marker: 1	Marker: 2
6 <206>FE-11-12 S6	0.500000 C	-110.9960 C	Off	Off
7 <207>FE-13-14 S7	0.200000 C	-116.2600 C	Off	Off

Time/Div: 02:00min y2:(Off) l2:(Off)  
y1:(Off) t1:(Off)  
Delta y: Delta t:

Externe 2	23.80200 C	Externe 5	25.77600 C	Externe 8	19.70400 C
Externe 3	24.48600 C	Externe 6	24.23200 C		
Externe 4	24.64100 C	Externe 7	24.03900 C		

Strip Chart

Channel Name	Units/Div	Reference	Marker: 1	Marker: 2
7 <315>FE-17-48 S7	0.500000 C	-90.79450 C	Off	Off
8 <316>FE-17-48 S8	0.500000 C	-87.59900 C	Off	Off

Time/Div: 02:00min y2:(Off) l2:(Off)  
y1:(Off) t1:(Off)  
Delta y: Delta t:

FE-1-2 S1	-67.85600 C	FE-9-10 S5	-108.0340 C
FE-3-4 S2	-89.67300 C	FE-11-12 S6	-111.6440 C
FE-5-6 S3	-89.41300 C	FE-13-14 S7	-116.6700 C
FE-7-8 S4	-103.0510 C	FE-15-16 S8	-121.8840 C

FE-17-48 S1	-94.03100 C	FE-17-48 S5	-91.50700 C
FE-17-48 S2	-90.58400 C	FE-17-48 S6	-94.17100 C
FE-17-48 S3	-89.79500 C	FE-17-48 S7	-91.94100 C
FE-17-48 S4	-93.84100 C	FE-17-48 S8	-89.24900 C

Strip Chart

Channel Name	Units/Div	Reference	Marker: 1	Marker: 2
1 <301>FE-ADAPT	0.100000 C	24.70450 C	Off	Off
2 <302>FE-DIFF	0.500000 C	62.55900 C	Off	Off

Time/Div: 02:00min y2:(Off) l2:(Off)  
y1:(Off) t1:(Off)  
Delta y: Delta t:

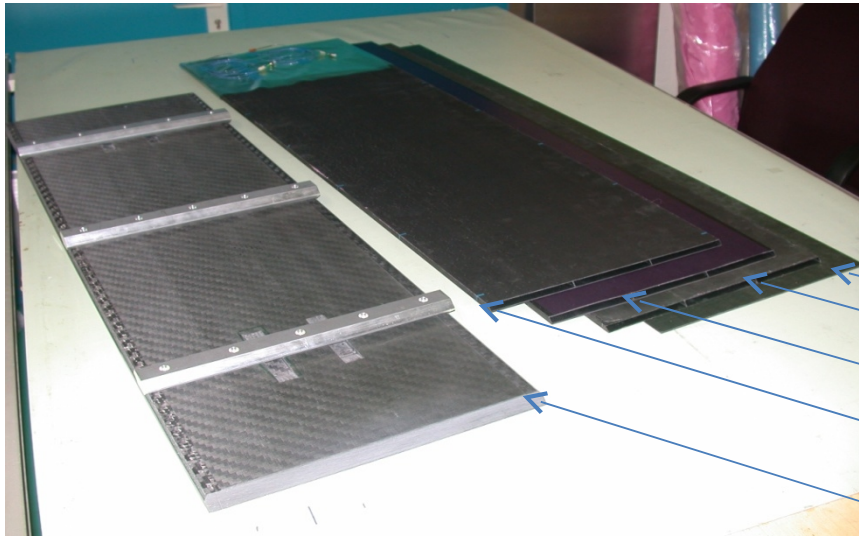
FE-ADAPT	25.10800 C	FE-DIFF	62.90700 C
Gre1	3.798875 Vdc	Gre2	2.036963 Vdc

Nouveau matériel détecté  
Lecteur de disque

00:00:09 to Scan Scans 485 02: 13:25

# Assembly of the Alveolar Structure for the Demonstrator

Mechanical Structure only slightly smaller than for EUDET Module

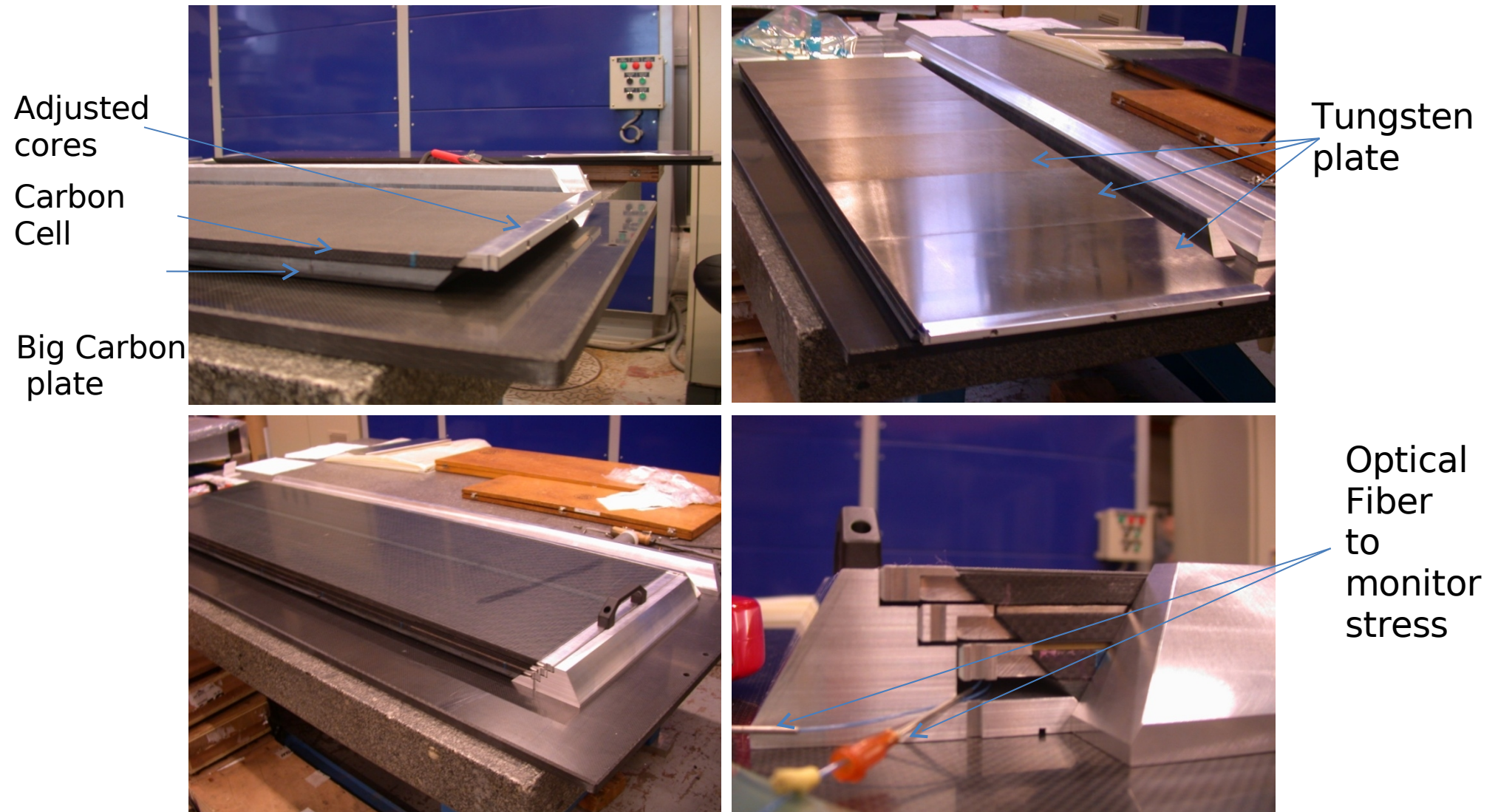


Small Plate  
Cell structure N°1  
Cell structure N°2  
Cell structure N°3  
Big Carbon plate



Final Temporary assembly

# Full Assembly



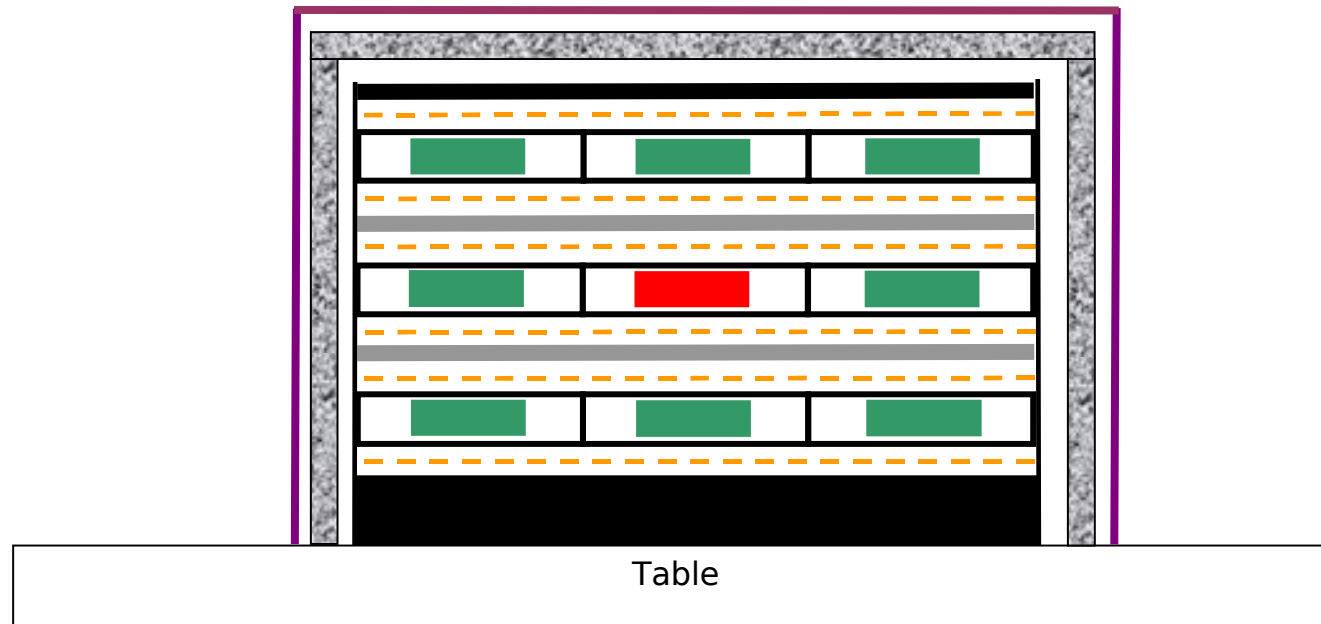
**...including Aluminum Cores and Assembly Mould**  
**Details by M. Frotin**

## What's next?

- Insertion of wrapped thermal slab into alveolar structure

Important step towards EUDET (and ILC!!!)

Details by J. Bonis



- Continuation of thermal tests with inserted thermal slab

Construction of heating mock-ups to establish realistic conditions

Time scale ~ September 2009



# Conclusion and Outlook

- Technical Design finished in Oct. 2008

Preparation of Demonstrator Tests since then

- Studies with the demonstrator

We have already learned a lot about the details of the mechanical construction

**Demonstrator studies finished by July 2009**

**(with extension in September 2009)**

**Will cover most if not all aspects described in EUDET proposal**

The collaboration is a real pleasure, thanks to everybody involved!!!

- Demonstrator studies should/will be summarised in a NIM paper  
(Strategy to be developed)

# Conclusion and Outlook cont'd

- Towards the EUDET Module
  - Moulds for H Structures and alveolar layers ordered  
Fabrication of full blown alveolar structure is EUDET deliverable  
**Expected beginning of June**
  - Assembly Hall for EUDET at LAL in preparation
  - “Wrapping” of Slab and Integration Cradle for 'real' slab
    - needs further study
    - needs special tools which are very expensive!!!!
  - Focus of getting the VFE accomplished in early 2010
    - Meeting EUDET Timeline with “intermediate” solution for VFE  
SPIROC in SKIROC on a FEV7, let's look for a few cosmics
    - Special (expensive) equipment and manufacturing procedures needed  
for mass production of chips and boards (See talk by Stephane)
    - Michele at LAL to strengthen communication between  
engineering and physics
  - “Shipping” signals out  
Interface to the DAQ and beyond will be addressed -> Daniel